

II. Method of Collection

Electronic applications and electronic forms are required from participants, and the primary methods of submittal are email and Internet transmission of electronic forms. Approximately 1% of the application and reference forms may be mailed.

III. Data

OMB Control Number: 0648–0568.

Form Number: None.

Type of Review: Regular submission.

Affected Public: Individuals or households; business or other for-profit organizations; not-for-profit institutions; State, Local or Tribal Government.

Estimated Number of Respondents: 3,496.

Estimated Time Per Response: Student tracker database form, 16 hours; graduate application form, 8 hours; undergraduate application form, 8 hours; reference forms, 1 hour; voluntary alumni update form, 1 hour.

Estimated Total Annual Burden Hours: 11,316.

Estimated Total Annual Cost to Public: \$300.

IV. Request for Comments

Comments are invited on: (a) Whether the proposed collection of information is necessary for the proper performance of the functions of the agency, including whether the information shall have practical utility; (b) the accuracy of the agency's estimate of the burden (including hours and cost) of the proposed collection of information; (c) ways to enhance the quality, utility, and clarity of the information to be collected; and (d) ways to minimize the burden of the collection of information on respondents, including through the use of automated collection techniques or other forms of information technology.

Comments submitted in response to this notice will be summarized and/or included in the request for OMB approval of this information collection; they also will become a matter of public record.

Dated: April 19, 2010.

Gwellnar Banks,

Management Analyst, Office of the Chief Information Officer.

[FR Doc. 2010–9316 Filed 4–21–10; 8:45 am]

BILLING CODE 3510–12–P

DEPARTMENT OF COMMERCE**International Trade Administration****West Virginia University, et al., Notice of Consolidated Decision on Applications for Duty-Free Entry of Electron Microscopes**

This is a decision consolidated pursuant to Section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89–651, as amended by Pub. L. 106–36; 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 A.M. and 5:00 P.M. in Room 3705, U.S. Department of Commerce, 14th and Constitution Avenue., NW, Washington, D.C.

Docket Number: 09–067. Applicant: West Virginia University, Morgantown, WV 26506. Instrument: Electron Microscope. Manufacturer: JEOL, Japan. Intended Use: See notice at 75 FR 13486, March 22, 2010.

Docket Number: 10–001. Applicant: United States Environmental Protection Agency, Cincinnati, OH 45268. Instrument: Electron Microscope. Manufacturer: JEOL, Japan. Intended Use: See notice at 75 FR 12175, March 15, 2010.

Docket Number: 10–003. Applicant: St. Lawrence University, Canton, NY 13617. Instrument: Electron Microscope. Manufacturer: FEI, Czech Republic. Intended Use: See notice at 75 FR 13486, March 22, 2010.

Comments: None received. Decision: Approved. No instrument of equivalent scientific value to the foreign instrument, for such purposes as these instruments are intended to be used, was being manufactured in the United States at the time the instruments were ordered. Reasons: Each foreign instrument is an electron microscope and is intended for research or scientific educational uses requiring an electron microscope. We know of no electron microscope, or any other instrument suited to these purposes, which was being manufactured in the United States at the time of order of each instrument.

Christopher Cassel,

Director, Subsidies Enforcement Office, Import Administration.

[FR Doc. 2010–9356 Filed 4–21–10; 8:45 am]

BILLING CODE 3510–DS–S

DEPARTMENT OF COMMERCE**International Trade Administration****University of Michigan, et al., Notice of Consolidated Decision on Applications for Duty-Free Entry of Scientific Instruments**

This is a decision pursuant to Section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89–651, as amended by Pub. L. 106–36; 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 A.M. and 5:00 P.M. in Room 3705, U.S. Department of Commerce, 14th and Constitution Ave., NW, Washington, D.C.

Comments: None received. Decision: Approved. We know of no instruments of equivalent scientific value to the foreign instruments described below, for such purposes as this is intended to be used, that was being manufactured in the United States at the time of its order.

Docket Number: 10–002. Applicant: University of Michigan, Ann Arbor, MI 49109–2122. Instrument: Tester for TFT Imager. Manufacturer: Siemens AG, Corporate Technology, Germany. Intended Use: See notice at 75 FR 12175, March 15, 2010. Reasons: This instrument must be capable of measuring dynamic rate, linearity and noise. It must also support voltages in the rate of -10 V to 20 V and support maximum 60 Hz scanning speed. Another pertinent specification for this instrument is that it must be capable of working with an imager, having 128 rows and 128 columns. We know of no instrument suited to these purposes, which was being manufactured in the United States at the time of order of this instrument.

Docket Number: 10–004. Applicant: State University of New York College at Geneseo, Geneseo, NY 14454. Instrument: MultiView 2000TS Microscope System. Manufacturer: Nanonics Imaging Ltd., Israel. Intended Use: See notice at 75 FR 13486, March 22, 2010. Reasons: A pertinent feature of this instrument is the ability to switch between scanning the tip and the sample stage. Other unique features include the ability to use conventional AFM type silicon cantilevers as well as cantilevered optical fiber probes with exposed probed geometry, providing normal force sensing; the capability to image side walls with an exposed tip glass AFM probe and the ability to image in both NSOM and AFM with AC operating modes. We know of no instrument suited to these purposes, which was being manufactured in the